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By: 

Date: March 19, 2003

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Alfred Kersch et al.

Applic. No. : 09/939,330

Filed : August 24, 2001

Title : Method of Producing a Ferroelectric Solid-State Layer Using an Auxiliary Substance

Examiner : Eric B Fuller

Group Art Unit : 1762

4/1/03
1/1/03
3/1/03
10/1/02
1/1/03
1/1/03

A M E N D M E N T

Hon. Commissioner of Patents and Trademarks,
Washington, D. C. 20231

S i r :

Responsive to the Office action dated December 19, 2002 kindly
amend the above-identified application as follows:

In the Claims:

Claim 1(amended). A method of producing a crystalline solid-state layer by chemical vapor deposition, which comprises: